

2814 #24

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

NISHIMOTO et al

Serial No.: 08/897,839

Filed: July 21, 1997

For: STRESS-ADJUSTED INSULATING
FILM FORMING METHOD,
SEMICONDUCTOR DEVICE AND
METHOD OF MANUFACTURING THE
SAME



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) Group Art Unit: 2814

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) Examiner: K. Eaton
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INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97(b)(1)

Assistant Commissioner for Patents
Washington, D.C. 20231

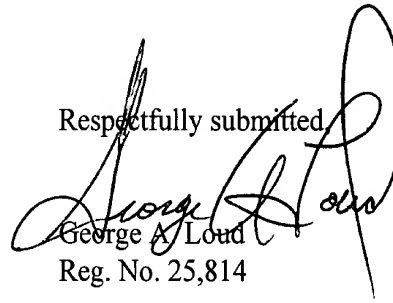
Sir:

It is respectfully requested that the examiner consider and cite of record Japanese Kokai Publications (18 month publications of unexamined applications) 8-203893 and 7-135205 which are listed on the attached. Copies of these Japanese Kokai Publications and English language abstracts thereof are submitted herewith.

The two publications submitted here are cited as document numbers (6) and (7) in a Japanese Office Action (copy attached) which issued December 12, 2000 in connection with Japanese

Application No. Hei 8-346,351, believed to correspond to the captioned application. The other documents (1-5) cited in the Japanese Search Report are already of record here.

Respectfully submitted,



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Dated: January 23, 2001

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